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XA-9387

PATENT APPLICATION 105
J. Mandler
6/27/02

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

Hitoshi TAKEUCHI

Appln. No.: 09/714,183

Group Art Unit: 2877

Filed: November 17, 2000

For: ABERRATION MEASURING APPARATUS, ABERRATION MEASURING METHOD, PROJECTION EXPOSURE APPARATUS HAVING THE SAME MEASURING APPARATUS, DEVICE MANUFACTURING METHOD USING THE SAME MEASURING METHOD, AND EXPOSURE METHOD

* * *

SECOND SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT
AND STATEMENT UNDER 37 C.F.R. § 1.97(e)

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

Supplementing the Information Disclosure Statement dated April 11, 2001, and without any assertion as to materiality or prior art effect, the documents listed on the attached Form PTO-1449 are hereby cited.

The documents on the attached List were recently cited in a foreign counterpart application.

The Commissioner is hereby authorized to charge to Deposit Account No. 50-1165 any fees under 37 C.F.R. §§ 1.16 and 1.17 that may be required by this paper, and to credit any overpayment to that Account.

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STATEMENT UNDER 37 C.F.R. § 1.97(e)

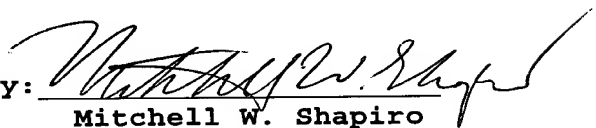
The undersigned hereby states that each item of information contained in this Information Disclosure Statement was first cited in any communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this Statement.

Respectfully submitted,

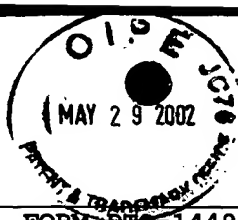
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May 29, 2002



FORM PTO-1449	Atty. Docket No. XA-9387	Appln. No. 09/714,183
<u>LIST OF DOCUMENTS CITED BY APPLICANT</u>	Applicant Hitoshi TAKEUCHI et al.	
	Filing Date November 17, 2000	Group 2877

U.S. PATENT DOCUMENTS

Examiner Initial		Document Number	Date	Name	Class	Sub-class	Filing Date
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

FOREIGN PATENT DOCUMENTS

Examiner Initial		Document Number	Date	Country	Class	Sub-class	Translation
	AL						
	AM						
	AN						
	AO						
	AP						
	AQ						

OTHER (including author, title, date, pertinent pages, etc.)

	Haig et al., "Effects of Wavefront Aberration on Visual Instrument Performance, and a Consequential Test Technique," <u>Applied Optics</u> , 2/1/87, Vol. 26, No. 3, pp. 492-500.
	Kitano et al., "Spherical Aberration of Gradient-Index Rod Lenses," <u>Applied Optics</u> , 2/83, Vol. 22, No. 3, pp. 396-399.

Examiner	Date Considered
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EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.